



<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	Atty Docket No. <b>NIKOP036/PA0498 00/04682</b>	Application No.: <b>10/761,436</b>
	Applicant: <b>W. Thomas Novak</b>	
	Filing Date <b>January 20, 2004</b>	Group <b>2878</b>

#### U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
Vm	A	6,400,441	06/04/02	Kenji Nishi, et al.	355	53	09/20/00
	B						
	C						
	D						
	E						
	F						
	G						

#### Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	H							
	I							
	J							
	K							
	L							

#### Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	M	
	N	
	O	
Examiner <i>V. N. Nelson</i>	Date Considered <i>18 July 2005</i>	

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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#### U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
vhn	A	6,208,407	03/27/01	Loopstra	255	53	07/13/98
vhn	B	5,917,580	06/29/99	Ebinuma, et al.	355	53	08/28/97
vhn	C	5,416,562	05/16/95	Ota, et al.	355	53	06/22/94
vhn	D	4,999,669	03/12/91	Sakamoto, et al.	355	53	07/12/89
	E						
	F						
	G						

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							Yes	No
vhn	H	EP 0 793 073 A2	03/09/97	EP			X	
vhn	I	EP 0 077 878 A1	04/05/83	EP			X	
	J							
	K							
	L							

#### Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
vhn	M	Patent Abstracts of Japan, Publication No. 61-196532, <i>Exposure Device</i> , Tsukamoto Izumi, filed 26/02/85.
vhn	N	Patent Abstracts of Japan, Publication No. 57-183031, <i>Method For Wafer Exposure And Device Thereof</i> , Iwai Hiroshi, filed 06/05/81.
	O	
Examiner: <i>Nelson Nelson</i>		Date Considered: <i>18 July 2003</i>

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.